Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

REMARKS

Claims 1-11, 13 and 15-18 are currently pending in this application,

Claims 12 and 14 having been canceled.

Claims 1-11, 13 and 15-18 have been rejected under 35 U.S.C. §103(a) as

unpatentable over Isomura et al (U.S. Patent No. 5,741,474) in view of

Schuessler et al (EP 0 878 442, to which a U.S. Patent No. 6,428,758 is a

counterpart). However, for the reasons set forth hereinafter, Applicants

respectfully submit that all claims of record in this application distinguish over

both Isomura et al and Schuessler et al, and are allowable. (Applicants'

comments as set forth herein are referenced to the U.S. '758 equivalent to the EP

Schuessler et al reference.)

The present invention is directed to a device for evaporating a liquid for a

reactor that has a plurality of chambers for carrying out a solid-catalyzed

reaction, each of the latter chambers including therein a catalyst material. A

common evaporating unit for evaporating liquid starting materials is provided in

thermal contact with the plurality of reaction chambers, which constitute the

catalytic reactor. According to a feature of the invention, as recited in Claim 1,

the portion of the evaporation unit in which evaporation of the liquid starting

materials substantially takes place is "at least partially surrounded by the

Page 2 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

plurality of chambers", each of which contains the catalyst material, and which

collectively form the reaction chamber. Claim 15 is similarly limited, reciting

that each of the chambers "contain[s] a catalyst material that is used in said

catalytic reaction", and that an interface between the evaporator unit and the

catalytic reactor is three dimensional, such that the evaporator is at least

partially surround by the plurality of chambers. The latter features are neither

taught nor suggested by either of the cited references.

Isomura et al, in particular, discloses a process and apparatus for

producing high purity hydrogen in which methanol, water and air are input to a

vaporization chamber 10 that is heated by a heater unit 9, as noted at Column 4,

lines 39-51. From there, the evaporated starting materials pass to a reforming

chamber 11, where they undergo reforming and partial oxidation in the presence

of the catalyst 12. The hydrogen gas generated by these reactions enters the

separated gas chamber 14 via a hydrogen permeable membrane 13, and is

recovered via a path 15.

The Office Action states at paragraph 3 that Isomura et al discloses

apparatus which includes a plurality of chambers containing catalysts 12.

However, based on the foregoing brief description, and based on a review of

Figure 1, as described at Column 4, line 19 through Column 5, line 25, and

especially Column 5, lines 9-19, Applicants respectfully submit that the Isomura

Page 3 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

et al apparatus does not include a plurality of chambers which comprise a

catalyst, as recited in Claims 1 and 15. In this regard, the Office Action refers to

the fact that the reforming chamber 11 is divided by the hydrogen separating

membrane to form the separated gas chamber therein. While the latter

proposition is correct, as can be seen from an inspection of Figure 1, the

separated gas chamber does not contain a catalyst material. In fact, its function

is simply to collect the hydrogen gas which passes through the membrane 13,

and the only "chamber" which contains the catalyst 12, is that formed by the left-

hand side of the reforming chamber 11.

More importantly, however, it is also true, as acknowledged in the Office

Action, that Isomura et al does not disclose (either expressly or by inference) that

the area of the evaporation unit in which evaporation of the liquid starting

materials substantially takes place "is at least partially surrounded by the

plurality of chambers". Apart from the fact that there is no a "plurality of

chambers" in Isomura et al, insofar as the reference discloses, the interface

between the vaporization 10 and the reforming chamber 11 is planar, as depicted

in Figure 2. Nothing in the specification suggests otherwise. Accordingly,

Isomura et al fails to teach or suggest that the area of the evaporation unit

where evaporation takes place is "at least partially surrounded by the plurality

of chambers", each of which chambers comprises a catalyst material as recited in

Page 4 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

Claims 1 and 15. Moreover, the interface between the evaporation unit and the

reaction chamber is not three dimensional as recited in Claim 15.

The latter omission in Isomura et al is said to be taught in the Schuessler

et al reference. Schuessler et al discloses a reforming reactor which includes an

evaporator body "that adjoins the reaction zone in a flush manner", as indicated

in the abstract. More specifically, as shown in the drawing figure, (which is a

lengthwise section through the reactor unit), the evaporator layer 1 is adjacent to

a catalyst layer 2, and the interface between the two is planar. This feature is

confirmed by the specification at Column 3, lines 36-38, which states that the

"evaporator body...abuts the reaction zone two-dimensionally".

possible, that the catalyst layer 2 is formed by a porous metallic matrix, with the

evaporator layer 1 and the catalyst layer 2 being formed by a single continuous

porous matrix, as noted in the specification at Column 5, lines 13-15.

As shown in the figure, in the Schuessler et al device, a plurality of feed

channels 6,7 are provided for supplying liquid and gaseous components to the

evaporator layer 1. In particular, the feed channels 6 supply a mixture of liquid

methanol and water, while the channels 7 supply air or another oxygen

containing gas. It is important to note in this regard that neither the feed

channel 6 nor the feed channel 7 contains any catalyst material at all, nor are

Page 5 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

those channels adjacent to the catalyst layer 2, which is separated from them by

the evaporator layer 1.

In addition, a plurality of outlet channels are provided at the side 9 of the

catalyst layer 2, for collecting the reacted reformate gas. Nothing contained in

Schuessler et al teaches or suggests that the interface 9 between the catalyst

layer and the outlet plate 8 (which includes the outlet channels 10) is anything

other than planar, or two-dimensional, as indicated at Column 3, lines 36-38.

Accordingly, it is apparent that the evaporation unit 2 is not "at least partially

surrounded by" a plurality of chambers which comprise or contain a catalyst

material, as recited in Claims 1 and 15.

The Office Action at page 3 states that the common evaporation unit

(evaporation layer 1) in Schuessler et al is in thermally conductive contact with a

plurality of chambers, referring to the feed channels 6,7. However, the feed

channels 6,7 neither contain nor comprise, nor are they adjacent to, a catalyst

material, since they are separated from the catalyst layer by the evaporation

layer 1. While the outlet channels 10 in the outlet plate 8 are adjacent to the

catalyst layer 2, it is clear that they do not surround the evaporator layer, nor

are they in thermal contact with it. Accordingly, nothing contained in Schuessler

et al teaches or suggests an arrangement in which an area of the evaporation

unit in which evaporation of the liquid starting materials substantially takes

Page 6 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

place is at least partially surrounded by the plurality of chambers, as recited in

Moreover, Schuessler et al contains no disclosure which Claims 1 and 15.

teaches or suggests a modification of Isomura et al to replicate the apparatus of

Claims 1 and 15, nor is it apparent how such a modification would take place,

given the substantial differences in the structure of the two devices. In addition,

no rationale has been articulated for such a modification, and given the structure

and direction of gas flow in Schuessler et al, if it were somehow incorporated into

Isomura et al, no heat would flow from the chambers 10 to the evaporation layer,

as is accomplished by the structure defined in Claims 1 and 15.

Claims 2 and 16 further recite that the evaporation unit is "entirely

surrounded by the chambers", which according to Claim 1 comprise a catalyst. It

follows from what has been said previously, that this feature of the invention is

also neither taught nor suggested by either of the cited references.

Finally, Claims 7 and 8 recite that the evaporation unit is coupled to the

plurality of chambers "such that the thermal coupling varies with a temperature

gradient in the evaporation unit" (Claim 7) and furthermore that such coupling

is "inversely proportional" to the temperature gradient. Neither reference

contains any discussion which is directed to this matter, or which teaches or

discusses the features of Claims 7 and 8. Accordingly, the latter claims further

distinguish over the references for these additional reasons as well.

Page 7 of 8

Reply Dated: April 18, 2005

Reply to Office Action Mailed December 16, 2004

Attorney Docket No. 1748X/50407

If there are any questions regarding this amendment or the application in

general, a telephone call to the undersigned would be appreciated since this

should expedite the prosecution of the application for all concerned.

If necessary to effect a timely response, this paper should be considered as

a petition for an Extension of Time sufficient to effect a timely response, and

please charge any deficiency in fees or credit any overpayments to Deposit

Account No. 05-1323 (Docket #1748X/50407).

Respectfully submitted,

Gary R. Edwards

Registration No. 31,824

CROWELL & MORING LLP

Intellectual Property Group

P.O. Box 14300

Washington, DC 20044-4300

Telephone No.: (202) 624-2500

Facsimile No.: (202) 628-8844

GRE:kms GRE:kms

360417v2